



Silicon Valley Toxics Coalition

Did You Know?

Water use and other Materials and Wastes Associated with Semiconductor Production

	One 6" wafer*	Intel Rio Rancho NM ** (5000/week x 52 weeks)	Projected 120 new fabs*** (annually based on projection)
Input			
cu. ft. <u>bulk gases</u>	3,200	832,000,000 (832 mil)	99,840,000,000 (99.8 bil)
cu. ft. <u>hazardous gases</u>	22	5,720,000 (5.72 mil)	6,864,000,000 (686.4 bil)
gals DI water	2,275	591,500,500 (591 mil)	70,980,000,000 (70.9 bil)
lbs <u>chemicals</u>	20	5,200,000 (5.2 mil)	624,000,000 (624 mil)
kw hrs electrical power	285	74,100,000 (74.1 mil)	8,892,000,000 (8.8 bil)
Output			
lbs sodium hydroxide	25	6,500,000 (6.5 mil)	780,000,000 (780 mil)
gals. waste water	2840	738,400,000 (738 mil)	88,608,000,000 (88.6 bil)
lbs hazardous waste	7	1,820,000 (1.8 mil)	218,400,000 (218.4 mil)
* Based on calculation by Graydon Larabee of Texas Instruments, 1993			
** Projections made based on Intel data. The facility fabricates 8 inch wafers.			
*** Projections from Semiconductor International magazine, 1997			